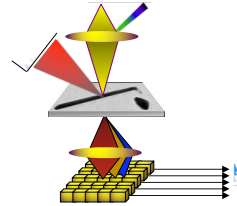
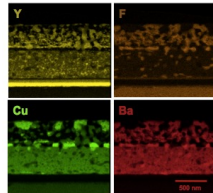
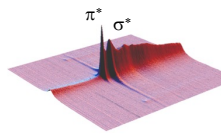
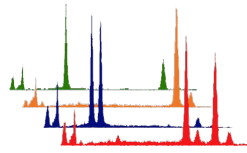


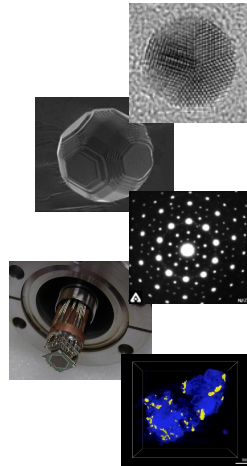
If you can't Detect it – Then you can't Measure it.



Nestor J. Zaluzec

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Photon Sciences Division

zaluzec@aesm.anl.gov
zaluzec@microscopy.com

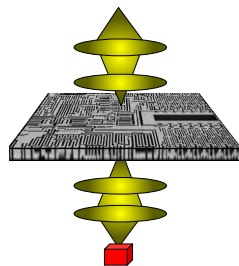


1

Types of Microscopes

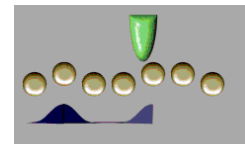
Microscopes with Lenses

Optical Microscopes
Electron Microscopes
Focused Ion Beam Microscopes
X-ray Microscopes



Microscopes without Lenses

Field Emission Microscopes/Atom Probes
Point Projection Microscopes
Scanning Probe Microscopes



2

2

Charged Particles (e^- , i^+) vs Photons (λ , x)

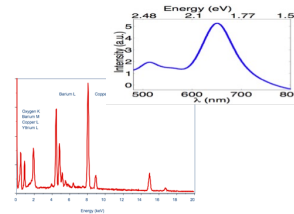
- Charged Particles are good for:

- High spatial resolution (< 1 nm routine)
- Probing /visualizing structure
- Various forms of Microanalysis (in-elastic scattering)
- Coupling to plasmons (loss function $\text{Im}\{1/\epsilon\}$)



- Photons are good for:

- In-situ & Atmospheric* Operation / In-Vivo Studies
- Various spectroscopies at high spectral (energy) resolution
 - Depending on technique $1 \text{ eV} \rightarrow 1 \mu\text{eV}$
 - Microanalysis (X-ray/Optical Spectroscopy)
- Thick/Bulk specimens (XRD/Synchrotrons)
- Coupling to electronic excitations/excitons
- Ultrafast (ps-fs) time resolution
- \$\$

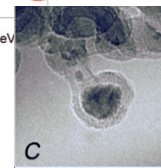
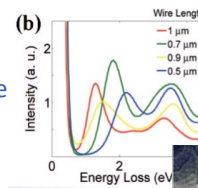


3

Charged Particles (e^- , i^+) vs Photons (λ , x)

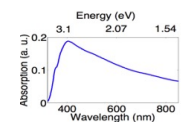
- Charged Particles are less desirable because

- The sample is ubiquitously damaged
- Time resolution is challenging
- Usually in Vacuum
 - In-situ possible but more difficult
- \$\$



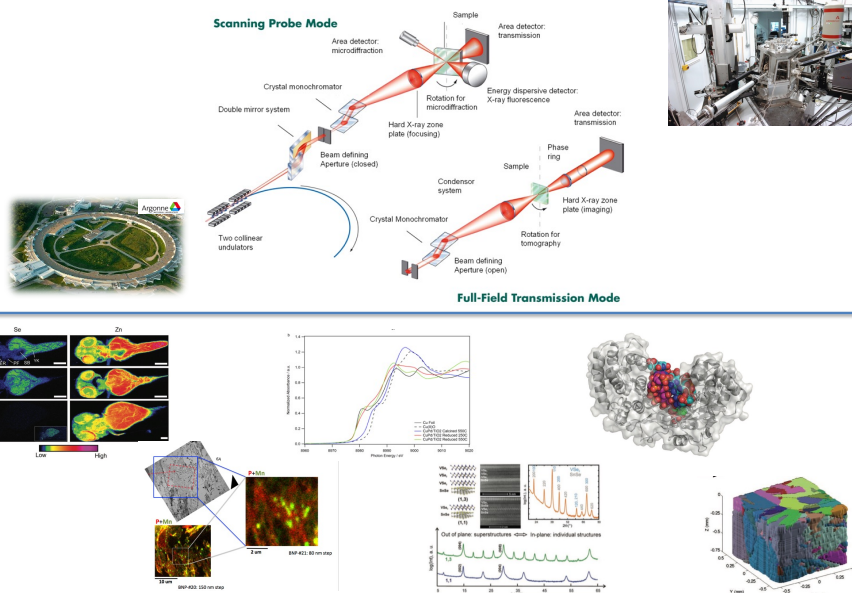
- Photons are less capable at:

- Very high spatial resolution
 - $\sim \lambda/2$ far-field, 30-200 nm in near field
- Non-transparent/thick specimens (visible light)
- Coupling to dark modes
 - forbidden excitons, plasmon polaritons



4

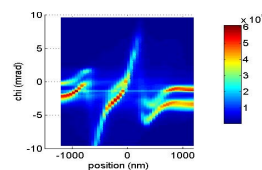
X-ray (Photon) Microscopy & Microanalysis



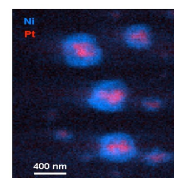
7

Hard X-ray Microscopy Capabilities at ANL/APS

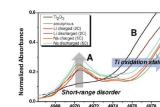
- **Current high-resolution capabilities at APS:**
 - CNM/APS Hard X-ray Nanoprobe, sector 26
 - 40 nm resolution in x-ray fluorescence, 30 nm resolution in transmission
 - Diffraction, fluorescence, tomography
 - APS Bio Nanoprobe, sector 21
 - 30 nm resolution, x-ray fluorescence
 - Cryogenic operation, cryogenic specimen transfer
 - Transmission X-ray microscope, sector 32
 - 30 nm resolution, transmission tomography
 - In-situ capabilities
- **In-Situ Nanoprobe Beamline (APS Upgrade)**
 - Science Thrust: Photovoltaics, Energy Storage, Nanoscale Electronics, Catalysis
 - 20 nm – 50 nm resolution at 10 – 1000x increased flux
 - In-situ fluorescence spectroscopy, tomography
 - Sensitivity to << 100 atoms in buried structures/interfaces
 - Coherent scattering to map defects at < 10 nm.



C. Murray et al. *Jour. Appl. Phys.* **109**, 083543 (2011)



Courtesy H. C. Kang



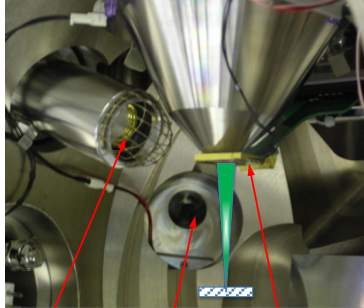
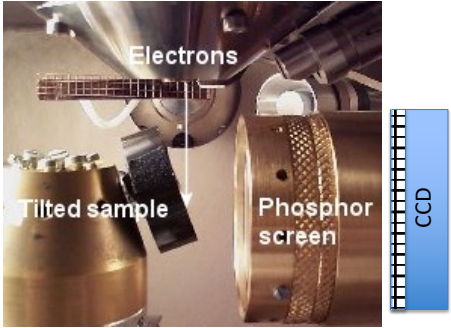
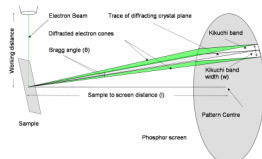


H Xiong et al., *J. Phys. Chem. Lett.*, **2**, 2560-2565 (2011)

Maser, ICXOM 2013

8

Imaging Detectors in Charged Particle Optical Systems

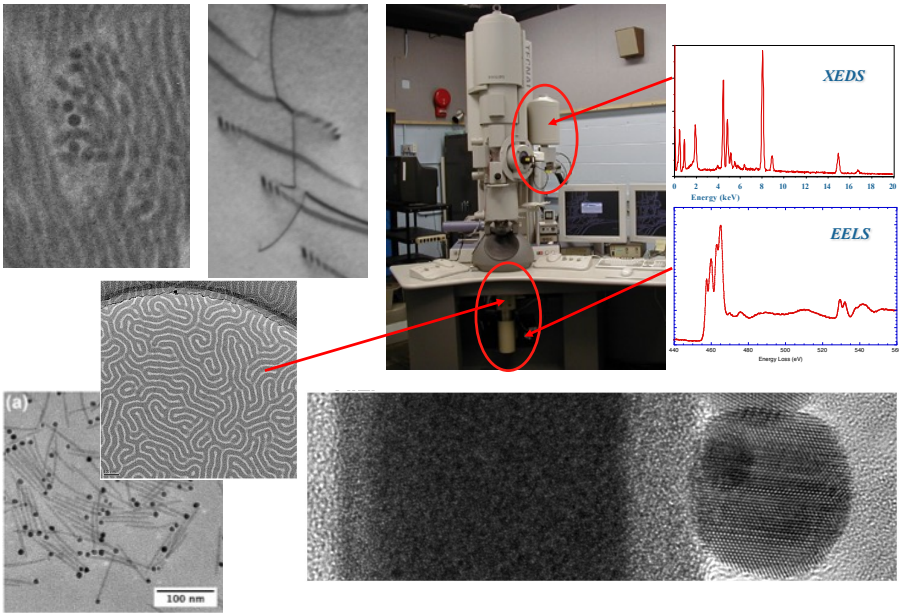
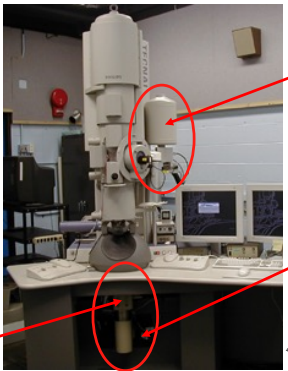
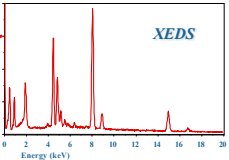
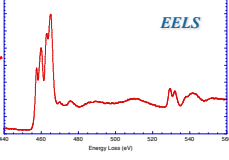
ET (PMT) Detector IR Camera Semiconductor Detector

Electrons Tilted sample Phosphor screen CCD

9

Transmission Electron Microscopy

Similar Range of Detectors for Imaging and Spectroscopy

(a)

100 nm

XEDS

EELS

10

Scanning Transmission Microscopy & Diffraction

Array Detectors
vs
Single or
Segmented Detector

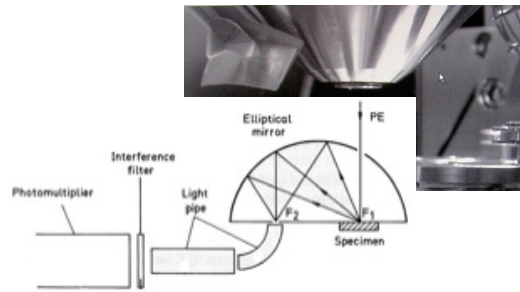
11

X-ray Detectors for Electron Beam Microanalysis

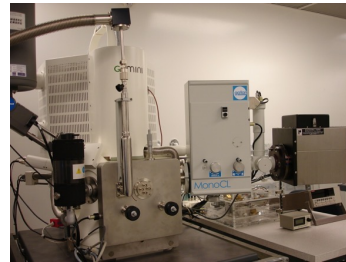
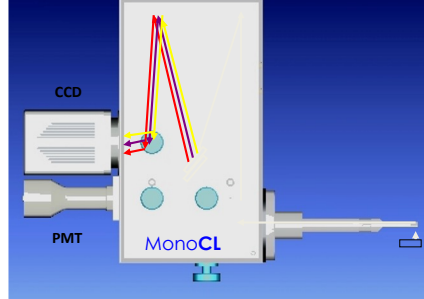
WDS EDS

12

Cathodoluminescence Instrumentation In Electron Microscopy

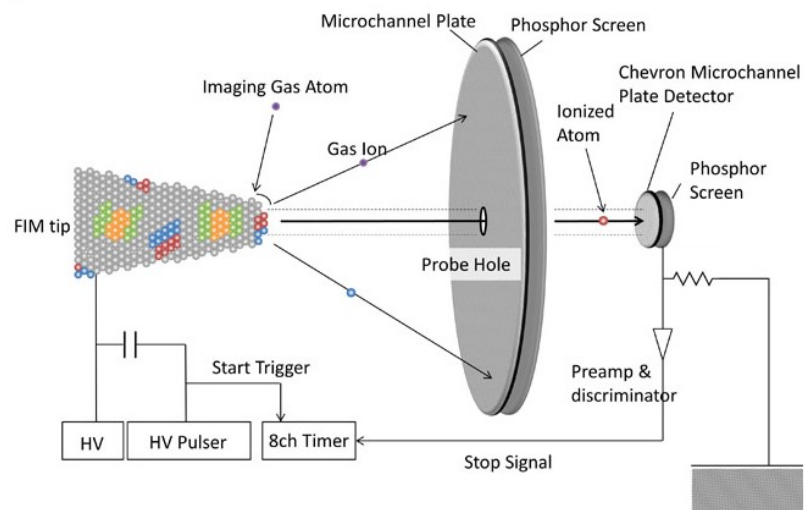


Employs multiple types of detectors



13

Atom Probe Field Ion Microscope



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Detectors

- Vacuum/Ionization devices: - Traditional Technology
 - o Photomultiplier Tubes (PMT)
 - o MicroChannel Plate (MCP)
 - o Hybrid Detectors (HD)
 - o Ion Detectors (ID)
 - o Ionization Chambers (IC)
- Solid State devices: Rapidly Evolving Technology
 - o PhotoDiodes (PD)
 - o Silicon Photomultipliers (SiPM)
 - o Avalanche Photo Diode : APD
 - o Geiger Mode APD : Arrays of SPAD: SiPM / MPPC ...
 - o Imaging devices: CCD and sCMOS, EMCCD
 - o X-ray Detectors: Si(Li), SDD....

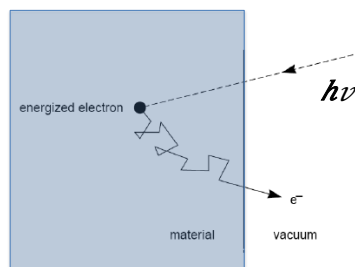


15

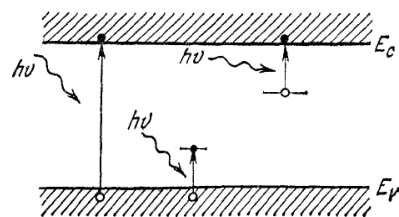
The photoelectric effect is generally responsible for the Signal ($h\nu$) detection by creating a measurable signal

Two types:

1. External: the Photo-electron is emitted into the vacuum from a photocathode material.
2. Internal: the Photo-electron is excited and occupies the conduction band of the semiconductor material, the photoconductive effect



External
PhotoElectron
escapes the material



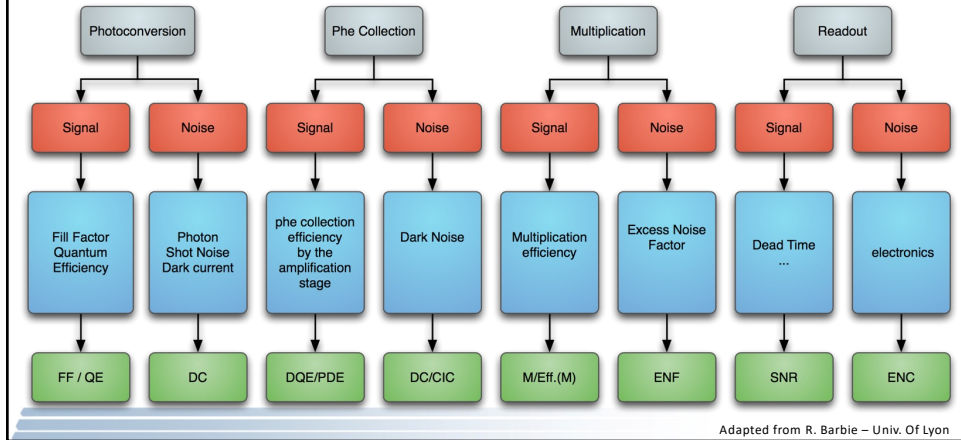
Internal
PhotoElectron
in the Conduction band

16

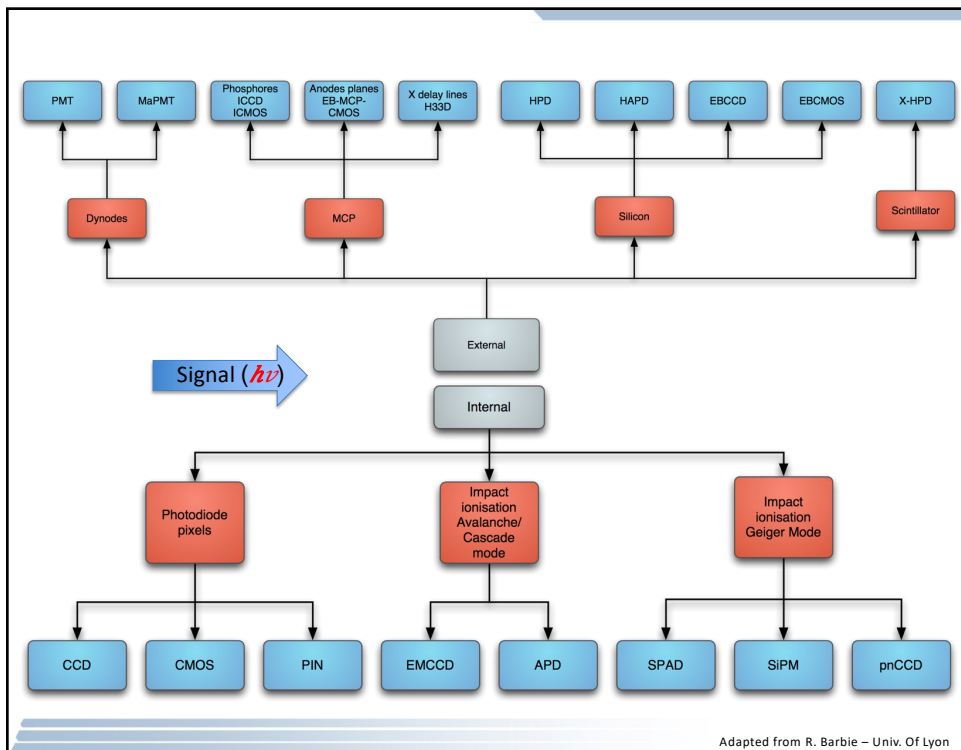
The 4 generic steps in the Detection process:

1. The initial charge carrier (pe, e/h) is produced by the Signal ($h\nu$)
2. The primary charge carrier is collected
3. The primary charge carrier is multiplied/amplified or not (CMOS/CCD/PD/SDD/Si-Li)
4. The secondary (or primary) charges are collected and read out

The measurement process is modified by noise sources and by signal collection inefficiency at each step:



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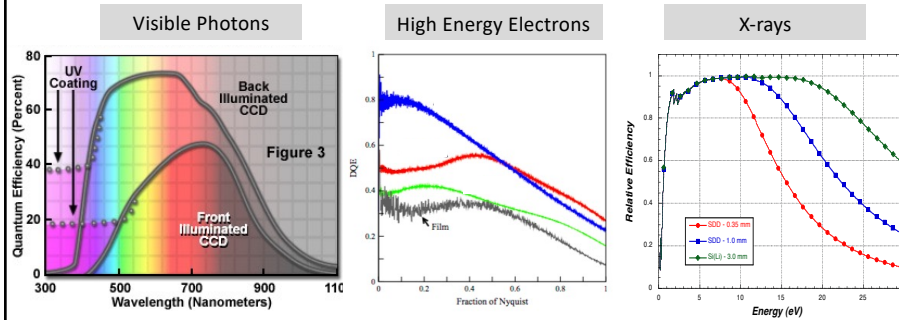
18

Detector Quantum Efficiency

Detector Quantum Efficiency (DQE): probability that a single event triggers a detectable output signal

$$DQE = \frac{\text{Output Signal}}{\text{Input Signal}} \leq 1$$

Different Detectors have Different DQE's



DQE of a "Detector" \neq DQE of the "Signal Processing Chain"

19

The choice of Detector should be made in light of the question:

What do you want to measure?

Choose your hierarchy of priorities:

- Counting ? Linearity ? Single Photon sensitivity ?
- Localize ? Imaging ? Large Field of View ? Detection surface ?
- dynamic range ?
- temporal resolution? dead time ?
- ...

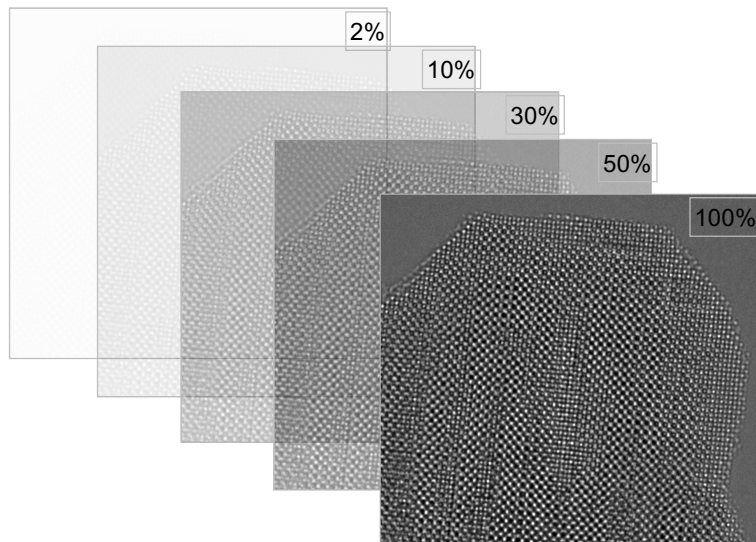
Different detectors exist and the "best" for the application is not always obvious.

The detection technologies are evolving rapidly.

Our speakers will be addressing the range typical to Microscopy/Microanalysis

20

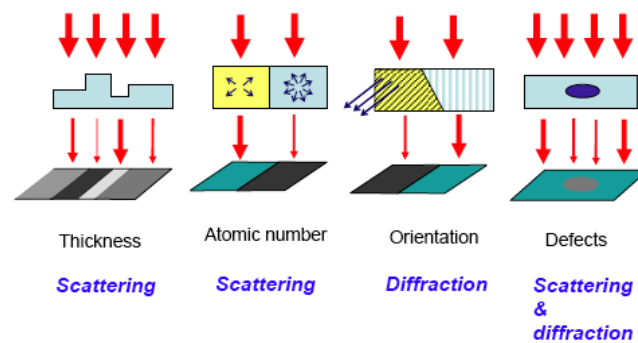
What is the limit ? Signal vs Contrast



$$Intensity = \Gamma_{\text{scatteringprobability}} \cdot N_{\text{atoms}} \cdot \eta_{\text{electrons}} \cdot \tau_{\text{time}} \cdot \Omega_{\text{efficiency}}$$

21

Factors Affecting Image Contrast (Physics vs Technology)



22

Contrast Mechanisms

Elastic

Amplitude (Mass/Thickness) Contrast
Varying mass of the specimen attenuates the beam

Diffraction Contrast

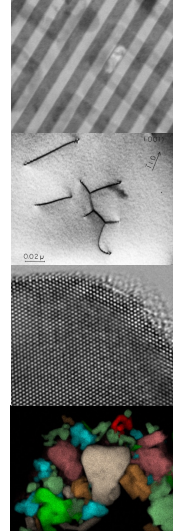
Scattered beams are removed or signal from scattered events is used

Phase (Interference) Contrast

Scattered beams constructively or destructively interact with each other

Inelastic

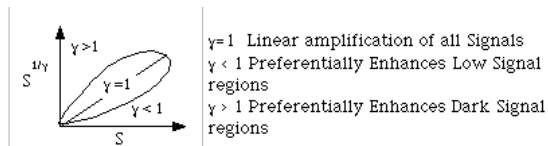
Signal derived from probe changing energy/momentum in the specimen



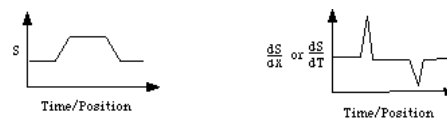
23



Black Level Suppression

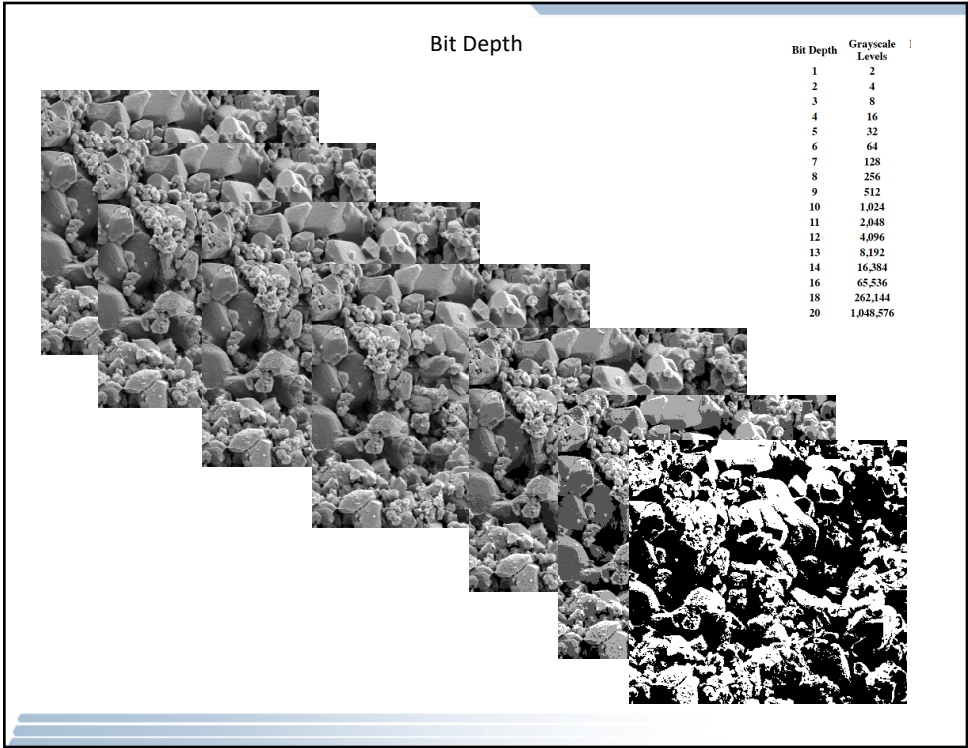


Non-Linear Amplification

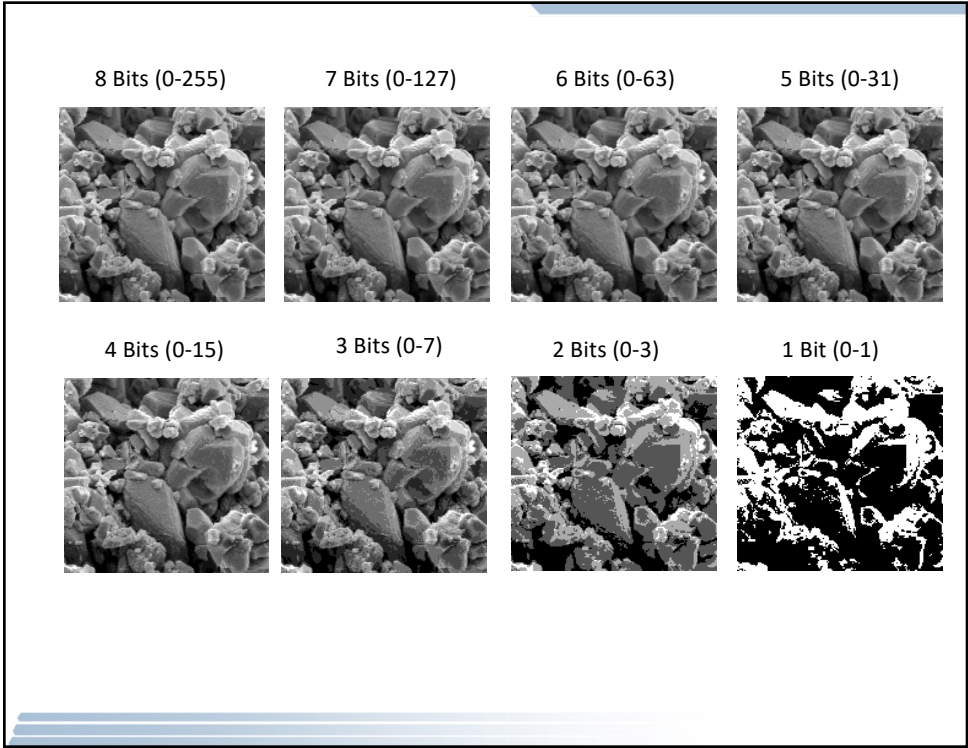


Differentiation

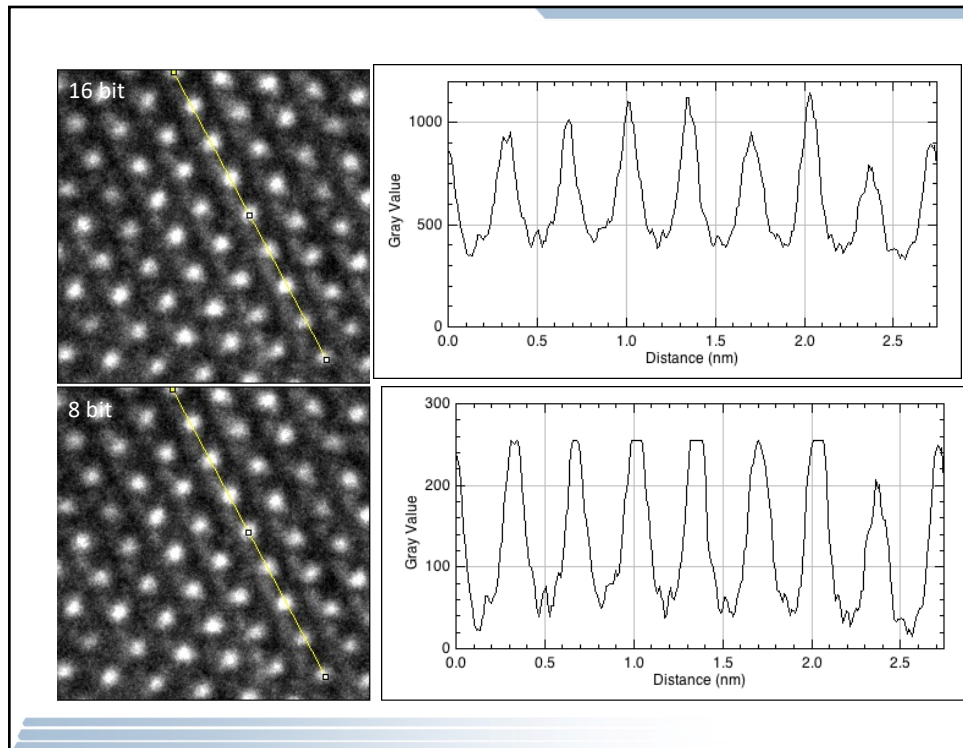
24



25

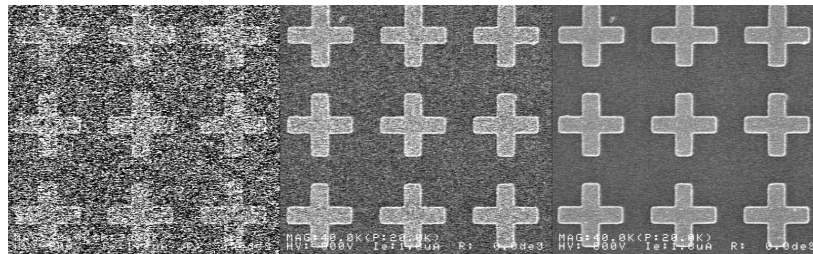


26



27

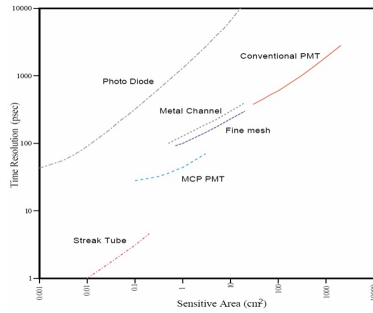
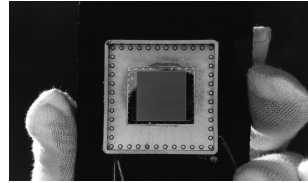
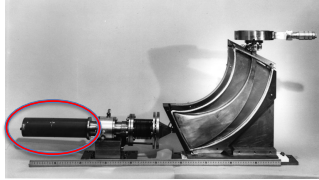
Signal-to-noise Ratio



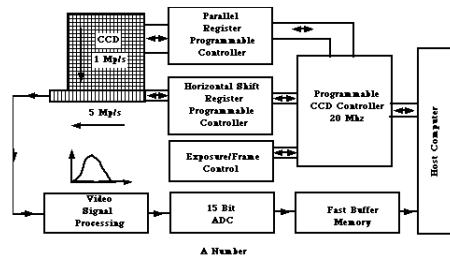
Collect data with adequate signal-to-noise ratio through image frame summation and/or by proper dwell time (pixel or frame time) setting.

28

Temporal Resolution



Single Event Detectors
counts/picosecond



A Number
Data Collection Parallel Detectors

Array Detectors
frames / sec

29

Part II



30